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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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APR 18 2005

Applicant: Hiroyuki NAKANO et al.

Serial No.: 10/075,244

Filed: 15 February 2002

For: METHOD AND APPARATUS FOR PLASMA PROCESSING

Group: 1762

Examiner: M. Padgett

Conf. No.: 7857

*Entered per  
RCE filed  
6/20/05  
cla*AMENDMENT AFTER FINAL AMENDMENT

Mail Stop AF  
EXPEDITED PROCESSING REQUESTED UNDER 37 CFR §1.116  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

18 April 2005

Sir:

In response to the final Office Action mailed 18 November 2004 in connection with the above-identified application, the following amendments and remarks are respectfully submitted.

In accordance with 37 CFR §1.121 in the Final Rule effective 30 July 2003, and as revised in the Final Rule effective 21 October 2004, each section of amendment begins on a new page, and changes are shown by strike-through (or double brackets where appropriate) and underlining to indicate deletions and additions, respectively. A complete listing of all claims ever presented in the application is given with the current status of each claim, and only the text of all pending and withdrawn claims is presented in full, with those pending/withdrawn claims not being amended herein being presented in clean version.